

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-10 (Canceled)

11. (Currently Amended) A process meter, comprising:
a sensor which can be mounted in a wall of a vessel for holding or conveying a process medium $[[,]]$;
an electronics case for meter electronics which is mechanically $[[,]]$ particularly rigidly $[[,]]$ coupled to said sensor $[[,]]$; and
at least one vibration absorber, wherein:
said electronics case is at least intermittently subjected to vibrations generated in or transmitted via said sensor $[[,]]$; and in order to reduce amplitudes of possible vibrations of said electronics case, said at least one vibration absorber which is vibrated at least intermittently in order to dissipate vibrational energy taken into said electronics case is affixed to a wall of said electronics case; and
said at least said vibration absorber is positioned at a distance from a joint between said sensor and said electronic case.

12. (Currently Amended) The process meter as set forth in claim 11, wherein:
said at least one vibration absorber is positioned ~~at a distance, particularly~~ as far as possible, from a joint between said sensor and said electronics case.

13. (Previously presented) The process meter as set forth in claim 11, wherein:
said at least one vibrated vibration absorber has a quality factor, Q_D , which is lower than a quality factor, Q_G , of said vibrating electronics case.

14. (Currently Amended) ~~The A process meter as set forth in claim 11,~~
~~wherein: , comprising:~~

a sensor which can be mounted in a wall of a vessel for holding or conveying a process medium;

an electronics case for meter electronics which is mechanically coupled to said sensor; and

at least one vibration absorber, wherein:

said electronics case is at least intermittently subjected to vibrations generated in or transmitted via said sensor, and in order to reduce amplitudes of possible vibrations of said electronics case, said at least one vibration absorber which is vibrated at least intermittently in order to dissipate vibrational energy taken into said electronics case is affixed to a wall of said electronics case; and

said at least one vibrated vibration absorber has a quality factor, Q_D , in the range of 1 to 5, particularly on the order of 3.

15. (Currently Amended) ~~The A process meter as set forth in claim 11,~~
~~wherein: , comprising:~~

a sensor which can be mounted in a wall of a vessel for holding or conveying a process medium;

an electronics case for meter electronics which is mechanically coupled to said sensor; and

at least one vibration absorber, wherein:

said electronics case is at least intermittently subjected to vibrations generated in or transmitted via said sensor, and in order to reduce amplitudes of possible vibrations of said electronics case, said at least one vibration absorber which is vibrated at least intermittently in order to dissipate vibrational energy taken into said electronics case is affixed to a wall of said electronics case; and

said at least one vibration absorber has a resonant frequency, f_D , which differs from a resonant frequency, f_G , of said electronics case by about 10% at the most.

16. (Previously presented) The process meter as set forth in claim 11, wherein:
said at least one vibration absorber has a resonant frequency, f_D , which is less
than a resonant frequency, f_G , of said electronics case.

17. (Currently Amended) ~~The A process meter as set forth in claim 11,~~
~~wherein: , comprising:~~

a sensor which can be mounted in a wall of a vessel for holding or conveying a
process medium;

an electronics case for meter electronics which is mechanically coupled to said
sensor; and

at least one vibration absorber, wherein:

said electronics case is at least intermittently subjected to vibrations generated
in or transmitted via said sensor, and in order to reduce amplitudes of possible
vibrations of said electronics case, said at least one vibration absorber which is vibrated
at least intermittently in order to dissipate vibrational energy taken into said electronics
case is affixed to a wall of said electronics case and, wherein:

said at least one vibration absorber has a mass, m_D , which is greater than 1%
of a mass, m_G , of said electronics case.

18. (Previously presented) The process meter as set forth in claim 11,
wherein:

said at least one vibration absorber is disposed within said electronics case.

19. (Currently Amended) ~~The A process meter as set forth in claim 11,~~
~~wherein: , comprising:~~

a sensor which can be mounted in a wall of a vessel for holding or conveying a
process medium;

an electronics case for meter electronics which is mechanically coupled to said
sensor; and

at least one vibration absorber, wherein:

said electronics case is at least intermittently subjected to vibrations generated in or transmitted via said sensor, and in order to reduce amplitudes of possible vibrations of said electronics case, said at least one vibration absorber which is vibrated at least intermittently in order to dissipate vibrational energy taken into said electronics case is affixed to a wall of said electronics case and,

said at least one vibration absorber comprises a disk- or cup-shaped plastic body having a ~~[[,]] particularly disk- or plate-shaped [[,]]~~ metal body fitted or embedded therein.

20. (Currently Amended) The process meter as set forth in claim 11, wherein:

said at least one vibration absorber comprises a plastic body which is affixed to the wall of said electronics case ~~[[,]] particularly with adhesive.~~

21. (Previously presented) The process meter as set forth in claim 11, wherein:

the process meter is selected from a group consisting of: level limit monitors; pressure gauges; electromagnetic flowmeters; vortex flowmeters; Coriolis mass flowmeters; densimeters, viscometers, ultrasonic flowmeters, and ultrasonic level meters.

22. (Previously presented) The process meter as set forth in claim 11, wherein:

said electronics case is screwed onto a necklike portion of the sensor.

23. (Previously presented) The process meter as set forth in claim 11, wherein:

said sensor is mounted in a wall of a pipe.

24. (Previously presented) The process meter as set forth in claim 11, wherein:

said sensor is mounted in a wall of a tank.

25. (Previously presented) A process meter, comprising:
a sensor for sensing at least one process variable, said sensor being mounted in a wall of a vessel,
an electronics case for meter electronics, said electronics case being mechanically coupled to said sensor, and said electronics case being at least intermittently subjected to vibrations; and
at least one vibration absorber for reducing amplitudes of vibrations of the electronics case, said at least one vibration absorber being located within said electronics case.

26. (Previously presented) The process meter as claimed in claim 25, wherein:
said at least one vibrated vibration absorber has a quality factor, QD, which is lower than a quality factor, QG, of said vibrating electronics case.

27. (Previously presented) The process meter as claimed in claim 25, wherein:
said at least one vibrated vibration absorber has a quality factor, QD, in the range of 1 to 5.

28. (Previously presented) The process meter as set forth in claim 25, wherein:
said at least one vibrated vibration absorber has quality factor, QD, on the order of 3.

29. (Previously presented) The process meter as claimed in claim 25, wherein:

said at least one vibration absorber has a resonant frequency, f_D , which differs from a resonant frequency, f_G , of said electronics case by about 10% at the most.

30. (Previously presented) The process meter as claimed in claim 25, wherein:

said at least one vibration absorber has a resonant frequency, f_D , which is less than a resonant frequency, f_G , of said electronics case.

31. (Previously presented) The process meter as claimed in claim 25, wherein:

said at least one vibration absorber has a mass, m_D , which is greater than 1% of a mass, m_G , of said electronics case.

32. (Previously presented) The process meter as claimed in claim 25, wherein:

said at least one vibration absorber comprises a disk- or cup-shaped plastic body having a metal body fitted or embedded therein.

33. (Previously presented) The process meter as set forth in claim 25, wherein:

said metal body is disk- or plate-shaped.

34. (Previously presented) The process meter as claimed in claim 25, wherein:

said at least one vibration absorber is affixed to a wall of said electronics case.

35. (Previously presented) The process meter as claimed in claim 25, wherein:

said at least one vibration absorber is positioned at a distance from a joint between said sensor and said electronics case.

36. (Previously presented) The process meter as set forth in claim 25, wherein:

said at least one vibration absorber is positioned as far as possible from the joint between said sensor and said electronics case.

37. (Previously presented) The process meter as set forth in claim 25, wherein:

said at least one vibration absorber comprises a plastic body which is affixed to the wall of said electronics case.

38. (Previously presented) The process meter as set forth in claim 25, wherein:

said at least one vibration absorber is affixed to the wall of said electronics case with adhesive.

39. (Previously presented) The process meter as claimed in claim 25, wherein: said electronics case is screwed onto a necklike portion of the sensor.

40. (Previously presented) The process meter as claimed in claim 25, wherein; said electronics case is rigidly coupled to said sensor.

41. (Previously presented) The process meter as claimed in claim 25, wherein; the vibrations, to which the electronics case is subjected at least intermittently, are generated in the sensor.

42. (Previously presented) The process meter as claimed in claim 25, wherein: the vibrations, to which the electronics case is subjected at least intermittently, are transmitted via the sensor.

43. (Previously presented) The process meter as claimed in claim 25, wherein:

the vessel, in which the sensor is mounted, is a pipe.

44. (Previously presented) The process meter as claimed in claim 25, wherein; the vessel, in which the sensor is mounted, is a tank.

45. (Previously presented) The process meter as claimed in claim 25, wherein: said process meter is selected from a group consting of level limit monitors, pressure gages, electromagnetic flowmeters, vortex flowmeters, Coriolis mass flowmeters, densimeters, viscometers, ultrasonic flowmeters, and ultrasonic level meters.

46. (New) The process meter as set forth in claim 14, wherein said at least one vibrated vibration absorber has a quality factor, Q_D , on the order of 3.

47. (New) The process meter as set forth in claim 19, wherein said metal body is disk- or plate-shaped.

48. (New) The process meter as set forth in claim 20, wherein plastic body which is affixed to the wall of said electronics case with adhesive.